

HITACHI

Pamphlet



Passing along the tradition from F to FX, a

ANTAS

SAM

Speedy Accuracy Maintainability

SFC1480FX SFC2480FX series

From F to FX: Passing along the tradition

Since the first of our SFC480 series, SAM brand highperformance mass flow controllers have been carrying forward a tradition. We use a waveform diaphragm made of a Ni-Co alloy (YET®101), developed by Hitachi Metals, which also proves that we are a manufacturer of high class metal materials. By employing this excellent diaphragm in the flow rate control valve, the key component in a mass flow controller, we incorporate a

simple valve design that does not use any sliding sections and reduces the occurrence of particulate contamination. With a high corrosion resistance and stable control performance, we leave the competition behind and our customers satisfied.



Diaphragm valve

Our flow rate sensor, another key component in mass flow controllers, employs a coil type thermal sensor based on technology we have been accumulating for half a century, and it is extremely reliable. In the SFC1480F series, thanks to the latest digital control technology, we have developed a dual-range

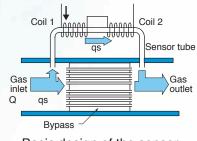
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mass flow controller, and a hybrid mass flow controller in which digital control technology reaches its peak. Our reputation is solid because our customers feel we offer an incomparable product.

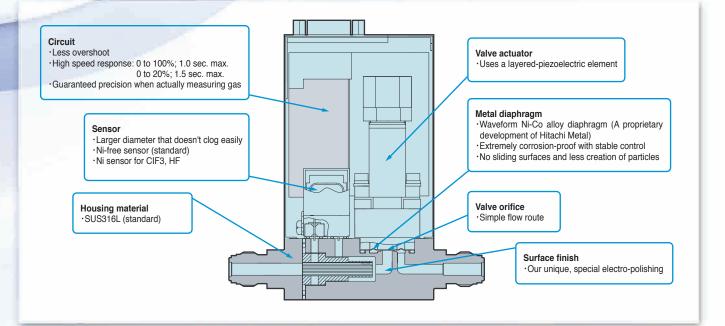


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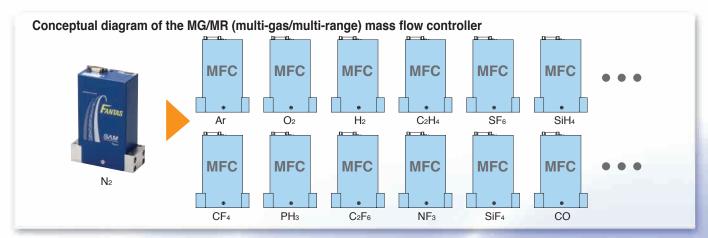
Basic design of the sensor

By inheriting the full tradition of the SAM brand, the SFC1480FX/SFC2480FX series are our most advanced models.



bold advancement to the next generation.

A bold advancement into the next generation, from G to FX



While inheriting the tradition of our earlier mass flow controllers, the SFC1480FX/SFC2480FX series is a bold advance into the next generation. The major element of innovation in this new series is the combination of many new technologies derived from the development of the G series all-in-one mass flow controller, in a new, next generation mass flow controller.

One core technology that has been fed back from this development is the MG/MR (multi-gas/multi-range) function. In conventional mass flow controllers, one controller could only handle one type of gas and one full scale flow rate range. This means that customers needed to have another mass flow controller for each different system, and for each different process recipe.

Since the FX series flow rate controller is equipped with the MG/MR function, and by preparing up to 14 recipes (full scale ranges of 2 SCCM to 50 SLM) to match the intended flow range, you can change the gas type and flow rate to match the actual gas you want to handle. When connected to a personal computer, the metering conditions can be changed instantly (See page 6).

Hitachi Metals actual gas flow rate accuracy guarantee system backs up this MG/MR function. A conventional mass flow controller only guarantees the flow rate precision with N₂ gas. To get the flow rate conditions for your actual gas using a conventional MFC, a conversion factor must be used as a coefficient to convert the flow rate.

Abbreviation	Standard full-scale flow rate range (N2 equivalent)
MG/MR	Flow range
FR-01	2~5 SCCM
FR-02	6~14 SCCM
FR-03	15~27 SCCM
FR-04	28~38 SCCM
FR-05	39~71 SCCM
FR-06	72~103 SCCM
FR-07	104~192 SCCM
FR-08	193~279 SCCM
FR-09	280~754 SCCM
FR-10	755~2037 SCCM
FR-11	2038~5500 SCCM
FR-12	5501~11000 SCCM
FR-13	11001~30000 SCCM
FR-14	30001~50000 SCCM

The reference values for these coefficients have been based of a variety of values, including calculated values, actually measured values, and empirical values. And, these were merely guidelines or reference values with some gas types. Although the MG/MR function is included, if the gas data deviates from the characteristics of the actual gas, the mass flow controller cannot perform as its designed level With the FX series mass flow controller, in addition to the flow rate reference for N₂ gas (that ensures conformance with the national standard using the conventional gravimetric method), we installed full scale actual gas metering and exhaust gas processing facilities at our factory. Using these facilities, measurement is made for each type of gas at each full-scale range, and record the data. This is then used as actual gas data.

The advancements in the FX series are not limited to the features above.

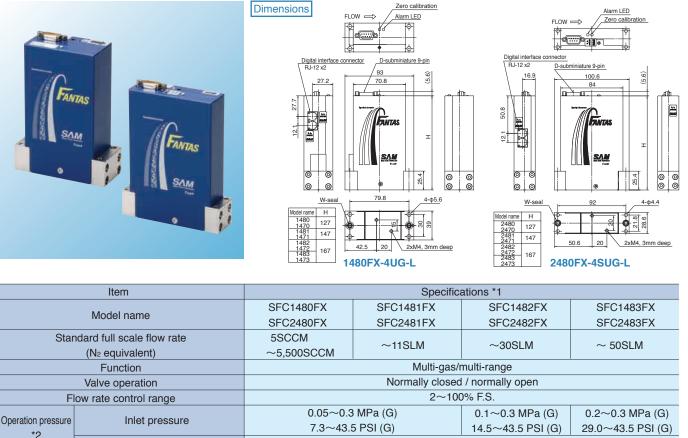
The PI (Pressure Insensitive) function improves the controller's ability to tolerate variations in the primary pressure. This function improves durability and is currently highly desired in mass flow controllers. The G1 series was developed from the G series as a mass flow controller containing a PI pressure sensor. The FX series inherited the PI technology of the G1 series. Although the FX series models do not have a pressure sensor, they employ a sensor method and housing that can be used with the new PI technology. So, even though the FX series is not as advanced as the G1 series with its full scale PI function, they have greater PI performance by design, when compared with the existing F series.



Actual gas flow rate measurement facility

SFC1480FX / SFC2480FX series

For both the 1.5" and 1.125"IGS MG/MR Mass Flow Controllers



Valve operation		Normally closed / normally open							
Flow rate control range		2~100% F.S.							
Operation pressure	Inlet pressure			3 MPa (G) 5 PSI (G)	0.1~0.3 MPa (G) 14.5~43.5 PSI (G)	0.2∼0.3 MPa (G) 29.0∼43.5 PSI (G)			
*2 Outlet pressure		Vacuum to ambient pressure							
	Proof pressure			1.0 MPa (G)	145 PSI (G)				
	Operati	ion		5~5	50 °C				
Temperature	Accuracy gua	ranteed		15~;	35 °C				
	Heating temperature v	when not powered			aximum				
	Humidity			· · · · · · · · · · · · · · · · · · ·	on condensing)				
	Installation position		Horizontal, Vertical	I	orizontal, Vertical (optic	on)			
	N ₂ gas	10~100%			+ 0.15% F.S.)				
Accuracy	112 940	2~10%		±0.2%					
, 100011009	Actual gas	10~100%		± (1.5% S.P. + 0.35% F.S.)					
		2~10%			% F.S.				
Linearity	N2 ga		±0.3% F.S.						
Enrodinty	Actual g	·	±1.0% F.S.						
Repeatability 10~100%		± (0.1% S.P. + 0.05% F.S.) ±0.06% F.S.							
	2~10	-							
Flow rate sensor	guaranteed zero poin		±0.5% F.S. / year, max.						
Temperature dependence		±0.01% F.S. / °C (15~35 °C)							
		Span	±0.01% S.P. / °C (15~35 °C) Max. 1.0 sec. to reach ±2% S.P of the set value.						
Response Time	ponse Time 0% → (20~100%)								
	$0\% \rightarrow (2\gamma)$	/	Max. 1.5 sec. to reach ±0.4% S.P of the set value.						
	ernal leakage stand		Max. $1x10^{-11}$ Pa · m ³ /s (He)						
	ow rate setting sign		0.1 to 5 VDC (absolute rating: Max. ±15 VDC)						
	ow rate output signa	al	0 to 5 VDC (maximum output: ±15 VDC)						
Required power		+15 VDC ±4%, 140 mA max							
		-15 VDC ±4%, 140 mA max SUS316L							
Material of gas	Housing, flange, valve seat		YET101 (Ni-Co alloy)						
wetted surface			9119	S316L	NI-CO alloy)	i			
Seal *3		SUS316L SUS316L							
		Specially electro-polished (standard)							
	Surface finish of components that contact the gas		W seal, C seal, H1G seal, 1/4" HMJ (UJR) male						
	Fitting *4								

*1: The specifications above are guaranteed values when the MFC was measured by itself in standard conditions. The MFC may not meet the specifications above, depending on the measurement conditions.

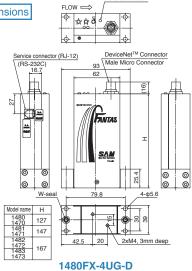
*2: The SFC147*FX/SFC247*FX are also available for use with minute pressure differences. Please inquire separately for the specifications of our minute pressure difference models. *3: A model using a rubber seal is also available. Please inquire separately about the rubber seal specifications.

*4: An H1G seal is only available on the SFC14**FX series

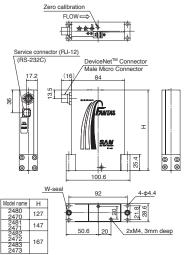
SFC1480FX-D / SFC2480FX-D series

DeviceNet[™] communication type For both the 1.5" and 1.125"IGS MG/MR Mass Flow Controllers





Zero calibration



2480FX-4SUG-D

Model name SFC2480FX-D SFC2481FX-D SFC2482FX-D SF Standard full scale flow rate 5SCCM SFC2481FX-D SF	C1483FX-D					
Standard full scale flow rate 5SCCM SFC2481FX-D SFC2482FX-D SF						
Standard full scale flow rate 5SCCM	C2483FX-D					
	~50SLM					
(N ₂ equivalent) ~5,500SCCM	- JUSEIW					
· · ·	Multi-gas/multi-range					
Valve operation Normally closed / normally open						
	2~100% F.S.					
Uperation pressure Intel pressure	~0.3 MPa (G) ~43.5 PSI (G)					
2 Outlet pressure Vacuum to ambient pressure						
Proof pressure 1.0 MPa (G) 145 PSI (G)						
Operation 5~50 °C						
Temperature Accuracy guaranteed 15~35 °C						
Heating temperature when not powered 65°C maximum						
Humidity 35~80%RH (non condensing)						
Installation position Horizontal, Vertical Horizontal, Vertical (option)						
N2 das	± (0.5% S.P. + 0.15% F.S.)					
Accuracy ±0.2% F.S.						
Actual gas	± (1.5% S.P. + 0.35% F.S.)					
±0.5% F.S.						
Linearity N2 gas ±0.3% F.S.	±0.3% F.S. ±1.0% F.S.					
	±1.0% F.S. ± (0.1% S.P. + 0.05% F.S.)					
	± (0.1% S.P. + 0.05% F.S.) ±0.06% F.S.					
	±0.06% F.S. ±0.5% F.S. / year, max.					
	±0.5% F.S. / year, max. ±0.01% F.S. / °C (15~35 °C)					
	±0.01% F.S. / °C (15~35 °C) ±0.01% S.P. / °C (15~35 °C)					
$0\% \rightarrow (20 \sim 100\%)$ Max 1.0 sec to reach +2% S.P. of the set value	$\pm 0.01\%$ S.P. 7 °C (15~35 °C) Max. 1.0 sec. to reach $\pm 2\%$ S.P of the set value.					
Response Time	Max. 1.5 sec. to reach $\pm 0.4\%$ S.P of the set value.					
External leakage standard Max. 1x10 ⁻¹¹ Pa • m ³ /s (He)						
Flow rate setting signal						
Flow rate output signal DeviceNet [™] communication *3						
Required power +24 VDC, 0.3 A max	+24 VDC, 0.3 A max					
Housing, flange, valve seat SUS316L						
Material of gas Diaphragm YET101 (Ni-Co alloy)						
wetted surface Flow sensor SUS316L Ni						
	SUS316L					
Seal *4 SUS316L	Specially electro-polished (standard)					

*1: The specifications above are guaranteed values when the MFC was measured by itself in standard conditions. The MFC may not meet the specifications above, depending on the measurement conditions.

*2: The SFC147*FX/SFC247*FX are also available for use with minute pressure differences. Please inquire separately for the specifications of our minute pressure difference models. *3: For information about DeviceNet[™] communication, see page 6.

*4: A model using a rubber seal is also available. Please inquire separately about the rubber seal specifications.

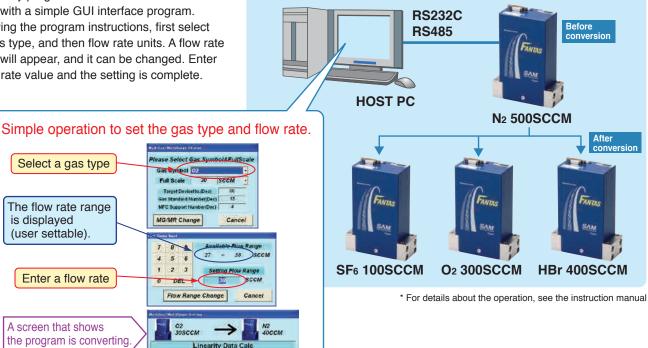
*5: An H1G seal is only available on the SFC14**FX series

How to use the MG/MR conversion program

Gas type and flow rate can be converting using an MG/MR conversion program. Connect the mass flow controller to a personal computer using a digital communication cable, and use our proprietary program. One can convert the data easily with a simple GUI interface program. Following the program instructions, first select the gas type, and then flow rate units. A flow rate range will appear, and it can be changed. Enter a flow rate value and the setting is complete.

Users can change the gas type and flow rate.

<MG/MR conversion program> Select the correction amount data according to the gas type and flow rate you want to control



Models compatible with the DeviceNet[™] communication system

About DeviceNet[™]

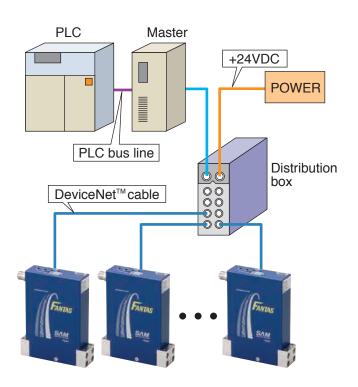
This is a field network recognized world wide, and it is approved as a standard sensor bus by the SEMI.

Field devices can be connected using serial communication in place of an I/O connection, allowing transfer of a large volume of data effectively.

The DeviceNet[™] specifications are administrated by the ODVA (Open DeviceNet Vendor Association, Inc.) a non-profit body established to promote the spread of this system world-wide.

What are the advantages of employing DeviceNet™

- By using serial communication from an I/O connection, one does not need an AD / DA / O board which can decrease configuration and set up costs.
- Only network cables are needed and this reduces cabling costs, which decreses required man-hours, shortening engineering periods, and avoids problems from incorrect wiring.
- DeviceNet[™] employs a CAN (Controller Area Network) as a communication controller, and you can use a variety of CAN error detection functions.
- 4) The DeviceNet[™] specifications are administrated by the ODVA, and have been normalized as international standards by IEC and SEMI. With this normalization, they are completely open, and lots of control devices are available from multiple venders. You can choose the optimum device for your application.
- 5) The power for DeviceNet[™] is only +24 VDC. You do not need to supply ±15 VDC for the mass flow controller.



Analog interface connector (D-Sub 9-pin)

Connector used : D-Subminiature, 9-pin connector (M3 screw)

Compatible plug : 17JE-13090-02 (D8B) (made by DDK) or equivalent

1) Connector model : L type

Pin number	Function
1	Valve open/close input (+15 VDC = Fully open; -15 VDC = Fully closed)
2	Output (0 to 5 VDC)
3	+15 VDC
4	COM (±15 VDC)
5	-15 VDC
6	Input (0.1 to 5 VDC)
7	COM (output)
8	COM (Input)
9	Valve valtage (0 to 5VDC)

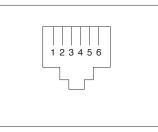
2) Connector model: Q type

Pin number	Function
1	Valve Full open (operate by connecting to COM)
2	Out put (0 to 5 VDC)
3	+15 VDC
4	COM (±15 VDC)
5	-15 VDC
6	Input (0.1 to 5 VDC)
7	COM (output)
8	COM (Input)
9	Valve Full-close (operate by connecting to COM)

Digital interface connector

Connector used : 43814-6621 (made by Molex) (RJ-12 x 2 connectors)

Pin number	Signal name				
	RS232C	RS485			
1	COM (Siginal)				
2	No Connection				
3	Rxd	RS-			
4	Txd	RS+			
5	N.C.				
6	N.C.				

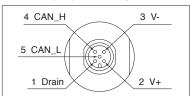


Note 1 : Rxd, Txd: RS232C Input and output Note 2 : RS-, RS+: RS480 Input and output

DeviceNet[™] connector

Connector used : DeviceNet[™] Male Micro Connector (CM02-8DR5P(D5) made by DDK, or equivalent)

Pin number	Signal name
1	Drain
2	V+
3	V-
4	CAN_H
5	CAN_L



Additional functions

Function name	Description	Setting and reading methods
Alarm function	See the item for the alarm function	By command
Flow sensor zero reset function	Reset the flow sensor zero	By command or when the switch on the top is pressed
Lamp response function	Reset the flow rate using a specified time for the step flow rate setting.	By command
Flow control valve voltage monitor output function	Set the flow control valve opening (0 to 5 VDC)	By command or analog voltage output (only L type)
Flow control valve fully open / close function	Open and close the flow control valve completely	By command, ±15 VDC, or contact point connection

Alarm function

Alarm cause	Alarm LED display	Alarm output condition
Normal operation	Green LED blinks at 1 Hz	No alarm
Flow rate setting does not the match	Red LED lights	The mis-match between the flow rate setting and the flow rate output is 10% or more of the full
flow rate output		scale and has continued for 10 seconds or longer
Abnormal ±15 VDC power supply	Turns off	The ± 15 VDC power supply is outside the range of ± 12 VDC to ± 17 VDC, and has been for 0.5 seconds or longer.
EEPROM access error	Red LED lights	Abnormal value in the EEPROM data.
Digital communication error	Red LED goes on	Did not receive a normal digital command
Change in flow rate control status	Red LED blinks at 2 Hz	The change in the preset value was 10% or more of the full scale and continued for 10 seconds
(Change from the preset status)		or longer.
·Flow rate setting changed		Or, the cumulative value of the zero point correction amount for the flow sensor is more than
·Flow rate output changed		±20% of full scale
·Flow control valve open level changed		
·Abnormal zero point		
correction value for the flow sensor		

Precautions to ensure safe use

In order to use our products safely, make sure to read the relevant instruction manuals before use.

			Model	name				
Controller or meter	Size	Temperature	Pressure	Flow range	Series	Seal	Operation	
SFC	1	4	8	2	FX	М	С	
SFC	Mass flow co	ntroller			1			
FMT	Mass flow me	eter						
	1	1.5" size						
	2	1.125" size	1					
		4	Normal tempe					
		5		ture type (80°C	,			
		6	-	perature type				
			8	Normal press	• •			
			1	0		CM (FR-01~11)	
				1	11 SLM (FR-1		1	
				2	30 SLM (FR-	,		
				3	50 SLM (FR-			
					FX		lti range, digital	
						M	Metal seal	
						R	Rubber seal	_
						,	Blank	Mass flow met
	1	Option		1	I		С	Normally close
Fitting	Connector	Gas-contact surface finish	Communication method	Protocol	Flow sensor material		0	Normally open
4UG	L		В	L	N			
4V *	1/4" HMJ (UJ	R) male						
4UG	1.5" W							
4AG 4H1G **	1.5" C	l /Litaabi ICS a						
461G 4SUG ***	1.125" W sea	ll (Hitachi IGS s	ear)					
4SAG ***	1.125 W sea							
	L	D-sub 9-pin (t	op mount), valv	ve fully open / f	ully closed sign	al, ±15VDC typ	be	
	Q	-			closed signal, C			
	T ***	D-sub 9-pin (ι	upstream side),	digital output t	уре			
	D	DeviceNet™						
		Blank	Special electro	•				
		K	Machine proc	1				
			Blank	RS232C or D	eviceNet™			
			В	RS485 Blank	SAM protocol	or DeviceNet [⊤]	м	
				L	protocol	of Devicervel		
				L	Blank	Ni free		
ote: * Can me	-	gap between the fa		(UJR) male.	N	Ni sensor		
		ies can be used wit	h a 4U1C fitting					

Hitachi Metals, Ltd.

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Sales agent:

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